

REMARKS

Claims 1-12 are pending. Claims 1-3 and 7-9 are withdrawn from consideration. Claims 4-6 and 10-12 have been rejected. Claims 4, 7 and 10-12- have been amended. Claims 13-18 have been added, as supported by Figure 3 and paragraphs 0023 and 0024. Claims 1-18 remain in the case.

Applicant respectfully requests that the foregoing amendments be made prior to further examination of the present application, and respectfully requests reconsideration of the present application in view of the foregoing amendments and the reasons that follow. This amendment adds, changes and/or deletes claims in this application. A detailed listing of all claims that are, or were, in the application, irrespective of whether the claim(s) remain under examination in the application, is presented, along with appropriate defined status identifiers.

It is noted that the withdrawn claims are process claims directed to a method of using the elected apparatus. Under the doctrine of *In re Ochiai*, process claims which depend from or otherwise include all the limitations of a patentable product claim are properly rejoined and examined with the product claims once allowable product claims have been indicated. Applicant has amended process claim 7 consistent with the amendment to claim 10. so that the criteria for rejoinder apply. Accordingly, the process claims remain in the case for reconsideration once an allowable apparatus claim has been indicated.

Claims 4-6 and 10-12 are rejected under 35 U.S.C. 112, second paragraph, as being indefinite for failing to particularly point out and distinctly claim the subject matter which applicant regards as the invention. Claims 4 and 10 have been amended to address the bases for the rejection, and reconsideration and withdrawal of the rejection is respectfully requested.

Claims 4, 5, 10 and 11 are rejected under 35 U.S.C. 103(a) as being unpatentable over Kawai (JP 2002-249868) taken in view of Van Slyke I (US 2003/0203638) and Nagashima (US 6,473,564). The examiner urges that Kawai discloses in Figs. 1-5 an organic EL thin film manufacturing apparatus comprising a vapor deposition apparatus comprising a line source 62 positioned in a vacuum chamber 20 and a material introducing part 30, wherein a vapor-state organic material is fed into the line source from the material introducing part to form a thin film of the organic material on a substrate disposed inside the vacuum chamber.

Van Slyke I is added as disclosing an organic EL thin film manufacturing apparatus comprising a vapor deposition apparatus comprising a line source 500VD positioned in a vacuum chamber 130C and a material introducing part 500VS, wherein a vapor-state organic material is fed into the line source from the material introducing part to form a thin film of the organic material on a substrate disposed inside the vacuum chamber, as in Kawai. The examiner further urges that Van Slyke I teaches in paragraphs 0016 and 0065 that it is advantageous to locate the material introducing part 500VS outside of the vacuum chamber 130C, so that the material introducing part 500VS can be detached from the vacuum chamber while maintaining the vacuum pressure in the vacuum chamber, such that it would have been obvious to one skilled in the art to modify Kawai to provide the material introducing part 30 of Kawai outside of the vacuum chamber.

The examiner states that Kawai and Van Slyke I do not discuss connecting the material introducing part to "an exhaustor that is independent to that of said vacuum chamber" as recited in claim 4. The examiner cites Nagashima for this feature, citing element 47 of Nagashima.

At the outset, it is noted that Kawai does not appear to disclose a line source. However, even if it is a line source, there is no suggestion in the combination of references that the material introducing part is connected to an exhaustor that is independent to that of the vacuum chamber, as presently recited in all of applicant's claims. The examiner has cited element 47 of Nagashima as teaching this feature. However, element 47 of Nagashima is the exhaustor for an inert gas. The organic material evaporation sources 121,122 have respective discharge ports 141, 142. When thin organic film materials are placed in the respective organic material evaporation sources 121,122 and heated to predetermined temperatures, the thin organic film materials emit vapors of organic compounds, which are discharged (desorbed) through the discharge ports 141,142 into the vacuum chamber 11. But these sources do not have their own exhaustors that are separate from the chamber exhaustor. Reconsideration and withdrawal of the rejection is respectfully requested.

Claims 6 and 12 are rejected under 35 U.S.C. 103(a) as being unpatentable over Kawai (JP 2002-249868) taken in view of Van Slyke I (US 2003/0203638) and Nagashima (US 6,473,564) for the reasons stated above, and taken in further view of Van Slyke II (2003/0015140). Van Slyke I is urged to teach in paragraph 0055 that his line source can have the same configuration as any of the tubular sources disclosed in US application 09/843,489, which has been published as Van Slyke II). Figs. 10, 16D, 16E and 16F of Van Slyke II are urged to show the use of a tubular source having a blocking plate for dispersing vapor as claimed in claim 6.

Van Slyke II does not overcome the failure of the other documents to teach connecting the material introducing part to an exhauster that is independent to that of the vacuum chamber. Accordingly, reconsideration and withdrawal of this rejection also is respectfully requested.

If there are any problems with this response, or if the examiner believes that a telephone interview would advance the prosecution of the present application, Applicant's attorney would appreciate a telephone call. In view of the foregoing, it is believed none of the references, taken singly or in combination, disclose the claimed invention. Accordingly, this application is believed to be in condition for allowance, the notice of which is respectfully requested.

Respectfully submitted,

ROSSI, KIMMS & McDOWELL LLP

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DATE

/BARBARA A. McDOWELL/

BARBARA A. McDOWELL

REG. NO. 31,640

P.O. Box 826

ASHBURN, VA 20146-0826

703-726-6020 (PHONE)

703-726-6024 (FAX)